

Docket No.: 50090-334

L. Nelson
#2/IDS
10/29/01

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Masanobu IWASAKI, et al.

Serial No.:

Group Art Unit:

Filed: August 23, 2001

Examiner:

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING POLISHING
SOLUTION, APPARATUS FOR AND METHOD OF POLISHING SEMICONDUCTOR
SUBSTRATE AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

1c971 U.S. PTO
09/934474
08/23/01

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

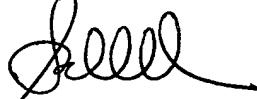
This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Serial No.:

Each non-English reference is accompanied by an English Abstract.

Respectfully submitted,

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